WE CLAIM:

1. A surface emitting laser, comprising:
a plurality of spaced apart mirrors;
a light amplifying region between said mirrors;
a substrate; and
a photon transparent ohmic contact for passing light energy therethrough whereby light emission through said surface emitting laser may be monitored.

2. The laser as set forth in claim 1, wherein said photon transparent ohmic contact is positioned on said substrate.

3. The laser as set forth in claim 1, wherein said photon transparent ohmic contact is positioned on an epitaxial side of said laser.

4. The laser as set forth in claim 1, wherein said surface emitting laser is a top emitting vertical cavity surface emitting laser.

5. The laser as set forth in claim 1, wherein said surface emitting laser is a bottom emitting vertical cavity surface emitting laser.

6. The laser as set forth in claim 1, wherein said transparent ohmic contact comprises a contact devoid of apertures.

7. The laser as set forth in claim 1, wherein said ohmic contact has a thickness between 1 nanometer and 100 nanometers.

8. The laser as set forth in claim 1, wherein said ohmic contact comprises indium tin oxide.

9. The laser as set forth in claim 1, wherein said mirrors have equivalent reflectivity.

10. The laser as set forth in claim 1, wherein said mirrors have reversed reflectivity.

11. A method for monitoring light emission from a surface emitting laser, said laser including:

a plurality of spaced apart mirrors;

a light amplifying region between said mirrors;

a substrate;

a photon transparent ohmic contact;

contacting said laser with a source of energy to generate light; and

monitoring emitted light transmitted through said transparent ohmic contact.

12. The method as set forth in claim 11, wherein said laser is a bottom emitting vertical cavity surface emitting laser.

13. The method as set forth in claim 12, further including the step of providing mirrors with equivalent reflectivity.

14. The method as set forth in claim 12, wherein said ohmic contact comprises indium tin oxide.

15. The method as set forth in claim 11, further including the step of providing mirrors with reversed reflectivity.

16. The method as set forth in claim 11, wherein said photon transparent contact is positioned on said substrate.

17. The method as set forth in claim 11, wherein said photon transparent contact is positioned on an epitaxial side of a bottom emitting vertical cavity surface emitting laser.